AMENDMENTS TO THE CLAIMS

The following listing of claims will replace all prior versions and listings of claims in the application.

LISTING OF CLAIMS

1. (Currently Amended) A semiconductor device comprising a field effect transistor formed on a SOI substrate, the semiconductor device characterized in comprising:

a gate region formed on a semiconductor film of the SOI substrate;
source and drain regions each spaced a specified distance from a channel
region formed in the semiconductor film below the gate region;

a first extension region <u>formed independently of the source region</u> that extends from the source region to the <u>channel region</u>; and

a second extension region <u>formed independently of the drain region</u> that extends from the drain region to the channel region,

wherein junction depths of the first and second extension regions are formed to be shallower than junction depths of the source region and the drain region.

- 2. (Original) A semiconductor device according to claim 1, wherein the junction depth of each of the first and second extension regions is 50% or less of the junction depth of each of the source region and the drain region.
- 3. (Original) A semiconductor device according to claim 1 or claim 2 characterized in operating in a fully depleted operation mode.

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4. (Original) A semiconductor device according to any one of claim 1 through claim 3, wherein the SOI substrate is a substrate composed of a glass substrate, a quartz substrate or another insulation substrate and a semiconductor film formed thereon.

5-8. (Cancelled)